



Attorney Docket No. 0756-7259

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Koichiro TANAKA et al.

Serial No. 10/787,120

Filed: February 27, 2004

For: LASER IRRADIATION METHOD,
LASER IRRADIATION APPARATUS,
AND METHOD FOR
MANUFACTURING
SEMICONDUCTOR DEVICE

) Group Art Unit: 2818

) Examiner: Chuong A. Luu

) CERTIFICATE OF MAILING

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) 2006.

) Adrian M. Stampen

)

AMENDMENT

Honorable Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Official Action dated June 8, 2006, please consider the following amendments and remarks in connection with the above-identified application.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 9 of this paper.